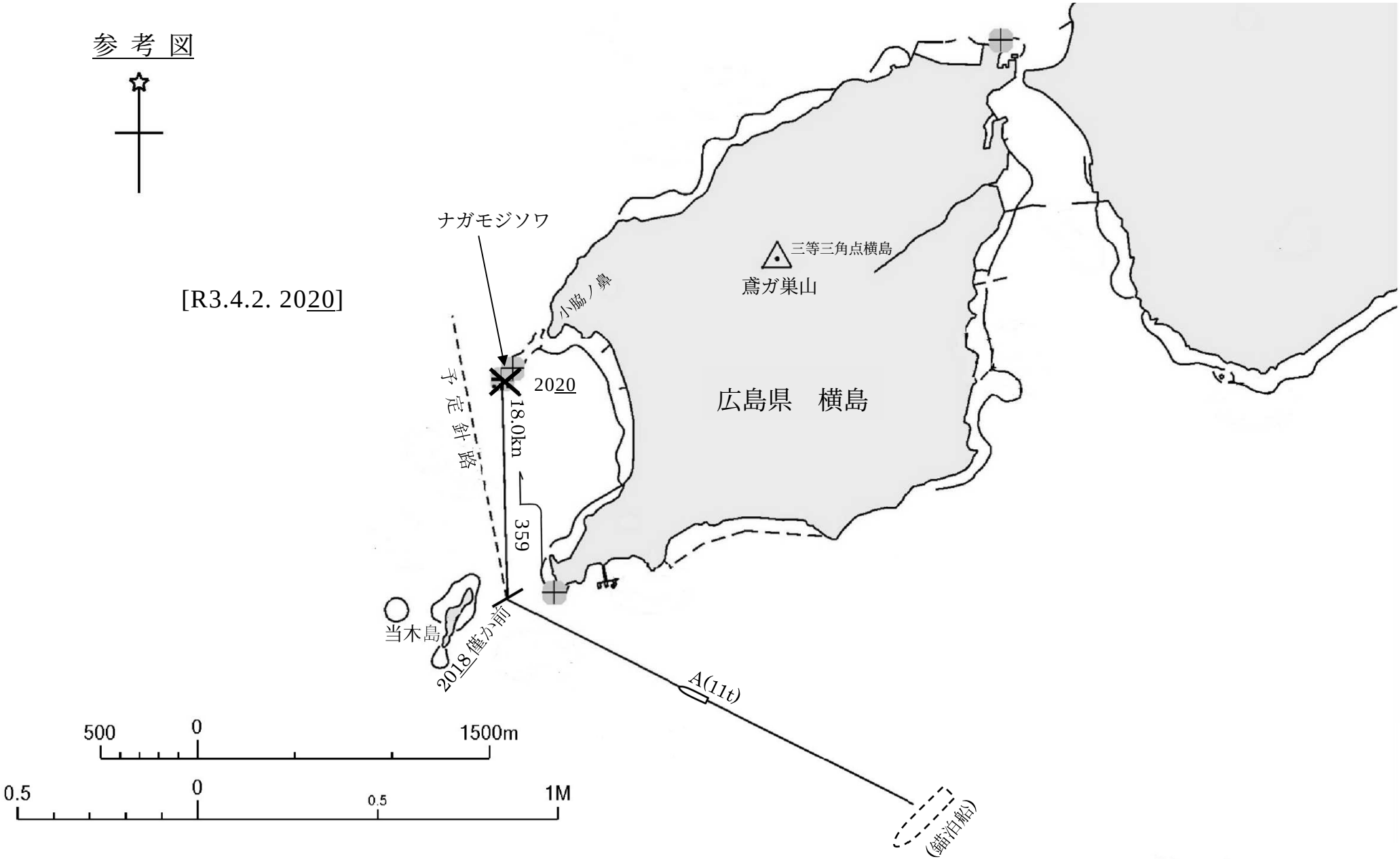
参 考 図

[R3.4.2. 2020]